

IN THE CLAIMS:

- (1) Please cancel claims 20-25 without prejudice.
- (2) Please add following new claim 26:
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26. A wafer conveyance system for transporting one or more of processed wafers among wafer processing apparatuses, each wafer processing apparatus having at least one insertion portion for receiving and sending processed wafers from a previous wafer processing apparatus and to a next wafer processing apparatus, the wafer conveyance system comprising:

a hermetically closed chamber being independent of each wafer processing apparatus and providing a isolated environment that is in communication with the at least one insertion portion of each wafer processing apparatus;

at least one guide path provided in the hermetically closed chamber; and

at least one mobile element being movable inside the chamber along the guide path with at least one processed wafer loaded thereon, the at least one mobile element being accessible to the at least one insertion portion of each wafer processing apparatus to transport at least one processed wafer with in the isolated environment from one wafer processing apparatus to another.
